

MEMS-BASED THERMOGRAVIMETRIC ANALYZER

Abstract of the Invention

A TGA based on a microelectromechanical system (MEMS) architecture and employing a flexural plate wave (FPW) mass sensor provides substantially improved mass sensitivity at a significantly reduced cost in comparison to traditional TGAs. The output of an FPW reference sensor is monitored to determine and compensate for any thermally-induced output of the FPW mass sensor.